

CERTIFICATE OF MAILING BY FIRST CLASS MAIL (37 CFR 1.8)			
Applicant(s): Takayoshi Sawayama		Docket No. OKI.201	
Serial No. 09/754,277	Filing Date 01/05/2001	Examiner L. Alejandro	Group Art Unit 1731

Invention: PLASMA ETCHING APPARATUS

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

Takayoshi Sawayama.

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Group Art Unit: 1731

Serial No.: 09/754,277

Examiner: L. Alejandro

Filed: January 5, 2001

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For: PLASMA ETCHING APPARATUS

GROUP 1731

Honorable Commissioner of Patents
Washington, D.C. 20231

Date: July 15, 2002

#5A
8/9/02
MW**Amendment**

Sir:

In response to the Office Action mailed February 13, 2002, the following amendments and remarks are respectfully submitted in connection with the above captioned application.

Submission of Certified Copy of Priority Document

A certified copy of the priority document, Japanese patent application number 2000-225686 is submitted herewith to ensure compliance with 35 USC § 119(b). Acknowledgement of the receipt thereof is respectfully requested.

In the Specification

(1.) At page 2, line 4, please replace the paragraph that begins "When the gas-introducing plate 4..." with the following paragraph:

When the gas-introducing plate 4 lying within the processing chamber of the

etching apparatus is used up, the gas-introducing plate 4 becomes thin as shown in

A1

Sw B1